

Amendments to the Abstract:

Please rewrite the Abstract as shown below:

ABSTRACT OF THE DISCLOSURE

There is disclosed aA method is provided for manufacturing method of a piezoelectric/electrostrictive film type device including a ceramic substrate, and a piezoelectric/electrostrictive operation portion containing including a lower electrode, a piezoelectric/electrostrictive layer, and upper electrode stacked on the substrate, and the. The piezoelectric/electrostrictive layer being is formed to extend beyond at least one of electrodes to form projected portions at its ends, the. The method comprising includes the steps of forming the piezoelectric/electrostrictive layer beyond at least one of electrodes to projectso that ends of the layer;piezoelectric/electrostrictive layer are projected to extend beyond ends of at least one electrode, applying a coating liquid in an a sufficient amount sufficient to makeso that the coating liquid permeate permeates through a gap between at least a the projected end portion of the piezoelectric/electrostrictive layer and the substrate, and so as to coat a predetermined portion of said the at least one of electrodes;electrode, and drying thus the applied coating liquid to form a coupling member to couple a the projected portion end portions of the piezoelectric/electrostrictive layer to the substrate. The piezoelectric/electrostrictive operation portion may be a multilayered structure.